

DAS

Environmental Experts.

PURPLE TECHNOLOGY FOR CLEAN AIR

Waste Gas Treatment | VOC Removal | Fine Dust Reduction



DAS WASTE GAS TREATMENT CONCEPTS

DAS waste gas treatment systems have been proven for more than 30 years in the global semiconductor industry and meet the highest standards of quality, safety and the demanding requirements of the German air pollution law (TA Luft). Based on these core competencies we develop and produce point-of-use abatement solutions for high waste gas flows for a wide variety of industries.

Furthermore, we also offer integrated abatement solutions. Our Integrated Pump and Abatement Solution (IPAS) creates the possibility to combine vacuum pumps from any vendor with a **DAS** abatement system; that means one cabinet with one control unit. Other abatement technologies such as cartridges and burn-boxes can also be integrated easily into the IPAS system.

In principle, **DAS** systems treat flammable, corrosive, reactive, toxic and/or pyrophoric gases (e.g. silanes, silane organics, hydrogen, ammonia or hydrogen halides) and fine dust. The **DAS** service team provides a 24/7 coverage worldwide on-site or on demand.

A flexible management of spare parts and consumables ensures maximum system uptime.

One key focus of **DAS** is Energy Efficient Waste Gas Treatment. We consult our customers to adapt the abatement settings to the actual process condition at the main tool. Our customers can optimize the COO by saving CH₄, O₂, water, cooling water and lye.

Waste Gas Treatment Systems



SALIX
Wet System



AQUABATE
Wet System



LARCH
Burn-Dry System



EDC
Particle Separator



DALEA
Particle Separator



ESCAPE
Burn-Wet System



STYRAX
Burn-Wet System



TILIA
Burn-Wet System



OPTIMUM
Burn-Wet System



TSUGA
Catalytic System

SERVICE FOR ABATEMENT SOLUTIONS

High-tech manufacturing processes are specific, so are DAS solutions for waste gas treatment, VOC removal and fine dust reduction. As a consequence the required service should be customized as well.

That is why we invest in the digital evolution of service and maintenance concepts allowing tools and facilities to connect for excellent performance.



Our products for your specific Application

Technology		SALIX	AQUABATE	LARCH	EDC	DALEA	ESCAPE	STYRAX	TILIA	UPTIMUM
		wet	wet	burn/ dry	dust	dust	burn/ wet	burn/ wet	burn/ wet	burn/ wet
Semiconductor Processes	Typical gases/ main components									
Etch	CF ₄ , SF ₆ , C ₄ F ₈						■	■	■	□
CVD	SiH ₄ , NH ₃ , TEOS, NF ₃				■	■	□	■	■	■
Epitaxi	H ₂ , SiH ₂ Cl ₂ , GeH ₄ , TCS		■		■	■	□	■	■	■
EUV	H ₂			■						
Wafer Cleaning	IPA, NH ₃ , HF	■	■							
Photovoltaic Processes	Typical gases/ main components									
CVD	SiH ₄ , NH ₃ , NF ₃ , TMAI				■	■	□	■	■	■
TFT-Processes										
CVD	SiH ₄ , NH ₃				■	■	□	■	■	■
LED-Processes	Typical gases/ main components									
MOCVD	H ₂ , NH ₃ , Metal organics		■	■			□	■	■	■

Your application is not listed? Please contact our sales team.

■ Recommendation
□ Possibility

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Waste Gas Treatment Systems



ROBINIA

Plasma-Wet System



SALIX

Wet System



AQUABATE

Wet System



LARCH

Burn-Dry System



EDC

Dust System



DALEA

Dust System



ESCAPE

Burn-Wet System



STYRAX

Burn-Wet System



TILIA

Burn-Wet System



OPTIMUM

Burn-Wet System



TSUGA

Catalytic System

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CVD	SiH ₄ , NH ₃ , TEOS, NF ₃				■	■	□	■	■	■
Epitaxi	H ₂ , SiH ₂ Cl ₂ , GeH ₄ , TCS		■		■	■	□	■	■	■
EUV	H ₂			■						
Wafer Cleaning	IPA, NH ₃ , HF	■	■							
Photovoltaic Processes	Typical gases/ main components									
CVD	SiH ₄ , NH ₃ , NF ₃ , TMAI				■	■	□	■	■	■
TFT-Processes										
CVD	SiH ₄ , NH ₃				■	■	□	■	■	■
LED-Processes	Typical gases/ main components									
MOCVD	H ₂ , NH ₃ , Metal organics		■	■			□	■	■	■

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